

OLIFF & BERRIDGE, PLC

ATTORNEYS AT LAW

Supplemental Application Data Sheet



Applicant Information

Applicant Authority type:: Inventor
Primary Citizenship Country:: Japan
Status:: Full Capacity
Given Name:: Makoto
Family Name:: NAKADATE
City of Residence:: Okaya-shi
Country of Residence:: JAPAN

Correspondence Information

Correspondence Customer Number:: 25944

Application Information

Application Type:: Regular
Subject Matter:: Utility
CD-ROM or CD-R: None
Title:: MASK, MANUFACTURING METHOD FOR MASK,
MANUFACTURING APPARATUS FOR MASK,
METHOD FOR MAKING FILM OF LIGHT-
EMITTING MATERIAL, ELECTROOPTICAL
APPARATUS AND ELECTRONIC APPARATUS
MASK, METHOD OF MANUFACTURING MASK,
DEVICE FOR MANUFACTURING MASK,
METHOD OF MANUFACTURING LAYER OF
LUMINESCENT MATERIAL, ELECTRO-OPTICAL
DEVICE, AND ELECTRONIC DEVICE

Attorney Docket Number:: 118824
Suggested Drawing Figure::
Total Drawing Sheets:: 9
Small Entity:: No

Representative Information

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Domestic Priority Information			
Application::	Continuity Type::	Parent Application::	Parent Filing Date::
Foreign Priority Information			
Country::	Application Number::	Filing Date::	Priority Claimed::
JAPAN	2003-061355	3/7/2003	Yes
Country::	Application Number::	Filing Date::	Priority Claimed::
JAPAN	2003-061356	3/7/2003	Yes
Country::	Application Number::	Filing Date::	Priority Claimed::
JAPAN	2003-061357	3/7/2003	Yes
Country::	Application Number::	Filing Date::	Priority Claimed::
JAPAN	2004-036621	2/13/2004	Yes
Assignee Information			
Assignee Name::	SEIKO EPSON CORPORATION		
Street of mailing address::	4-1, Nishi-shinjuku 2-chome, Shinjuku-ku,		
City of mailing address::	Tokyo,		
Country of mailing address::	JAPAN		